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		- 10	01 001105	Application Number	10/608,194		
			CLOSURE	Filing Date	June 30, 2003		
STAT	EMENT BY	A	PPLICANT	First Named Inventor	Byung II KWAK et al.		
				Group Art Unit	2811 2823		
(4	use as many shee	ets as	necessary)	Examiner Name	Unassigned M. Estrada		
Sheet	1 .	of	1	Attorney Docket Number	40296-0021		

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Examiner Initials *	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²				
Me	A01	F. SCOTT JOHNSON et al., "Selective Chemical Etching of Polycrystalline SiGe Alloys with Respect to Si and SiO ₂ ", Journal of Electronic Materials, 1992, pp. 805-810, Vol. 21, No. 8					
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Examiner	LA	Micholdo.	() Air da	Date	alit	ML
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